



UNITED STATES PATENT AND TRADEMARK OFFICE

UNITED STATES DEPARTMENT OF COMMERCE
 United States Patent and Trademark Office
 Address: COMMISSIONER FOR PATENTS
 P.O. Box 1450
 Alexandria, Virginia 22313-1450
 www.uspto.gov

BIBDATASHEET

CONFIRMATION NO. 4337

Bib Data Sheet

SERIAL NUMBER 10/603,924	FILING OR 371(c) DATE 06/24/2003 RULE	CLASS 438	GROUP ART UNIT 2813	ATTORNEY DOCKET NO. JC-7109-CIP
APPLICANTS Shao-Chung Hu, Taipei, TAIWAN; Teng-Chun Tsai, Hsinchu, TAIWAN; Chia-Lin Hsu, Taipei, TAIWAN; Yung-Tsung Wei, Tainan Hsien, TAIWAN;				
** CONTINUING DATA ***** This application is a CIP of 09/854,006 05/10/2001 PAT 6,696,361 <i>TN</i>				
** FOREIGN APPLICATIONS ***** <i>None</i> <i>TN</i> TAIWAN 90109738 04/24/2001				
IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 11/11/2003				
Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 (a-d) conditions <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after met Verified and <i>Allowance</i> Acknowledged <i>Chen</i> Examiner's Signature Initials		STATE OR COUNTRY TAIWAN	SHEETS DRAWING 4	TOTAL CLAIMS 12
		INDEPENDENT CLAIMS 2		
ADDRESS 23900				
TITLE METHOD OF REMOVING CONTAMINANTS FROM A SILICON WAFER AFTER CHEMICAL-MECHANICAL POLISHING OPERATION				
FILING FEE RECEIVED 750	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:		<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time) <input type="checkbox"/> 1.18 Fees (Issue) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit	



UNITED STATES PATENT AND TRADEMARK OFFICE

UNITED STATES DEPARTMENT OF COMMERCE
 United States Patent and Trademark Office
 Address: COMMISSIONER FOR PATENTS
 P.O. Box 1450
 Alexandria, Virginia 22313-1450
 www.uspto.gov



Bib Data Sheet

CONFIRMATION NO. 4337

SERIAL NUMBER	FILING OR 371(c) DATE	CLASS	GROUP ART UNIT	ATTORNEY DOCKET NO.
10/603,924	06/24/2003	438	2813	JC-7109-CIP
APPLICANTS Shao-Chung Hu, Taipei, TAIWAN; Teng-Chun Tsai, Hsinchu, TAIWAN; Chia-Lin Hsu, Taipei, TAIWAN; Yung-Tsung Wei, Tainan Hsien, TAIWAN;				
** CONTINUING DATA ***** <i>tn</i> This application is a CIP of 09/854,006 05/10/2001 PAT 6,696,361 ** FOREIGN APPLICATIONS ***** <i>tn</i> TAIWAN 90109738 04/24/2001				
IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 11/11/2003				
Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 (a-d) conditions <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after allowance Verified and Acknowledged <i>tn</i>		STATE OR COUNTRY TAIWAN	SHEETS DRAWING 4	TOTAL CLAIMS 12
INDEPENDENT CLAIMS 2				
ADDRESS 23900				
TITLE METHOD OF REMOVING CONTAMINANTS FROM A SILICON WAFER AFTER CHEMICAL-MECHANICAL POLISHING OPERATION				
FILING FEE RECEIVED 750	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:		<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time) <input type="checkbox"/> 1.18 Fees (Issue) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit	